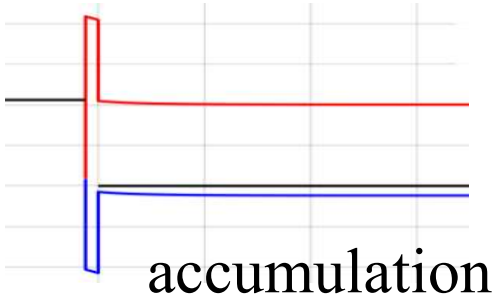
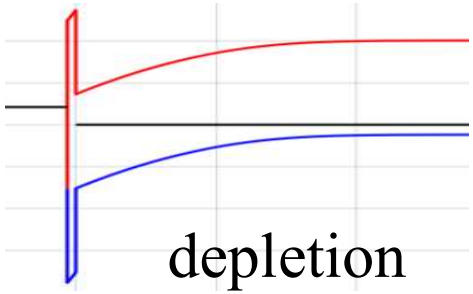
MOSFETs: Gradual Channel Approximation

Gradual channel approximation

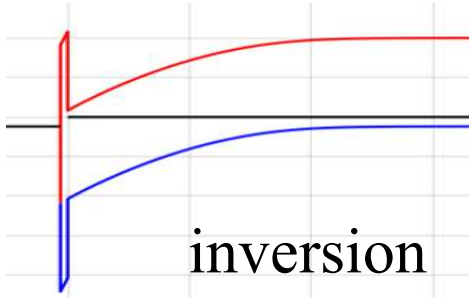


accumulation

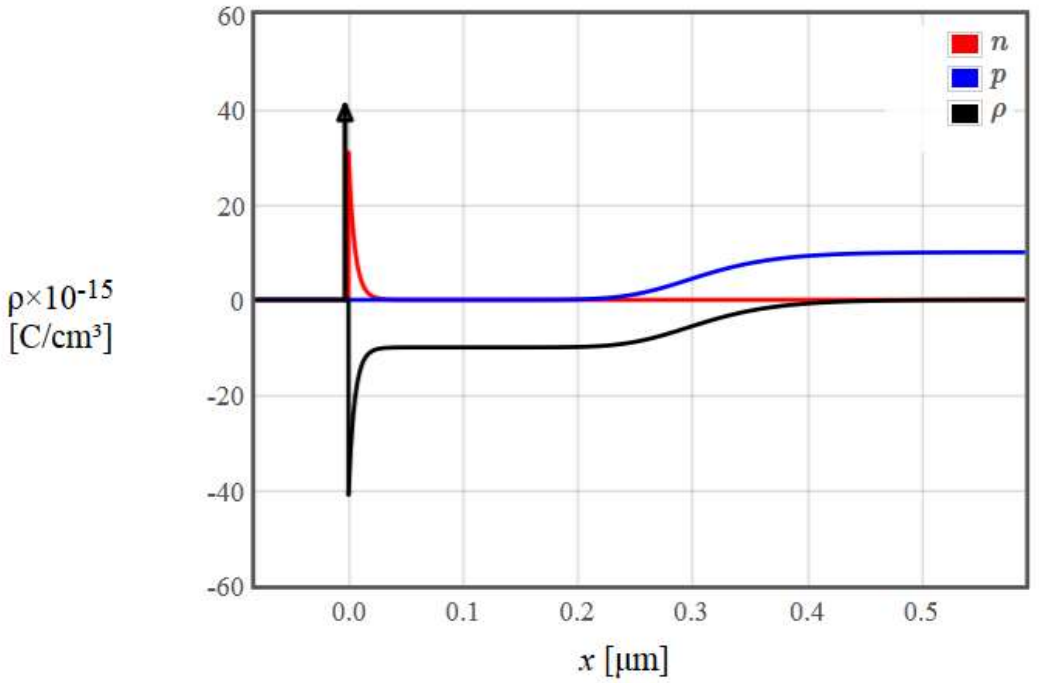
$$Q_{\text{mobile}} = \begin{cases} 0, & \text{for } V_G - V_B < V_T \\ -C_{\text{ox}}(V_G - V_B - V_T) & \text{for } V_G - V_B > V_T \end{cases}$$



depletion



inversion

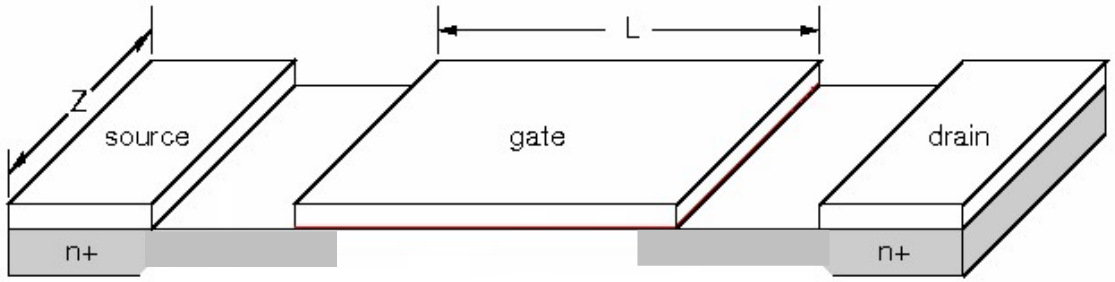


http://lampx.tugraz.at/~hadley/psd/L10/gradualchannelapprox.php

Gradual channel approximation

Ohm's law $\longrightarrow$ $j = -nev_d = ne\mu_n E_y$

$$I = Ztj = Ztne\mu_n E_y = Ze\mu_n n_s E_y$$



$n_s = nt$ is the sheet charge at the interface.

$$n_s(y) = -\frac{Q}{e} = \frac{C_{ox}\left(V_G - V_{ch}(y) - V_T\right)}{e}$$

Gradual channel approximation

$$n_s(y) = -\frac{Q(y)}{e} = \frac{C_{ox}(V_G - V_{ch}(y) - V_T)}{e}$$

$$I = Ztj = Ztnev_d = Zen_s\mu_n E_y$$

$$I_D = -Z\mu_n C_{ox}(V_G - V_{ch}(y) - V_T)\frac{dV_{ch}}{dy}$$

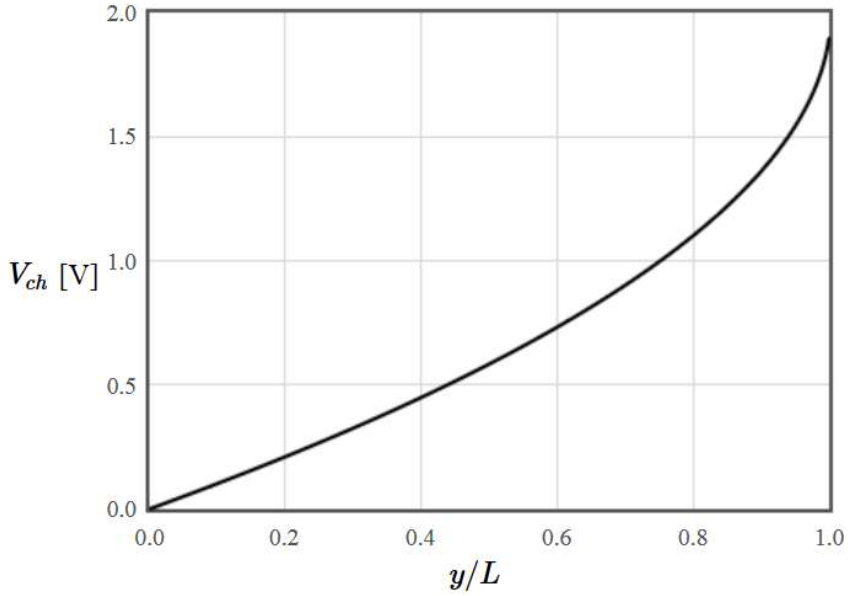
differential equation for V_{ch}

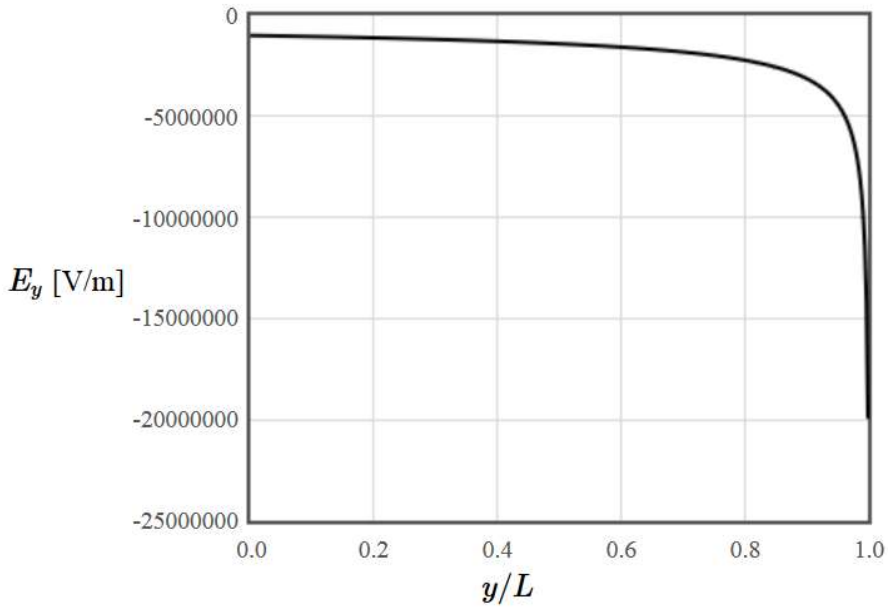
http://lampx.tugraz.at/~hadley/psd/L10/gradualchannelapprox.php

Gradual channel approximation

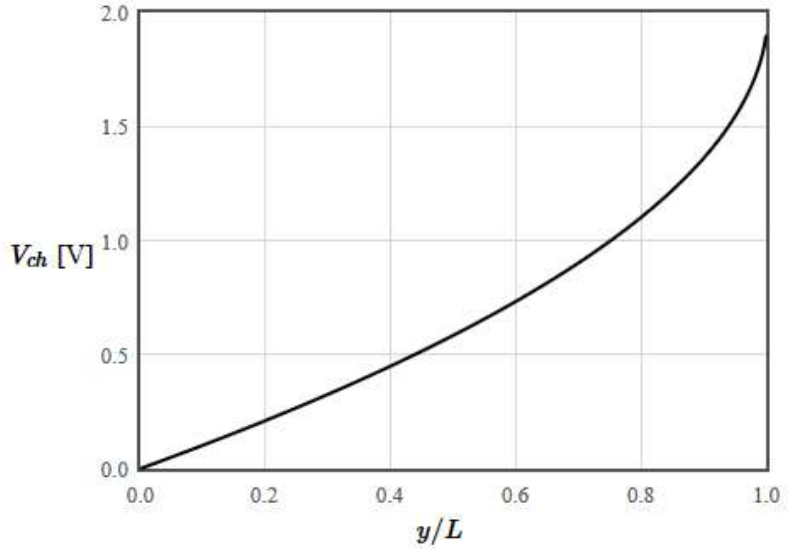
$$V_{ch}(y) = V_G - V_T - \sqrt{(V_G - V_T)^2 - \frac{2I_D y}{Z\mu_n C_{ox}}}$$

$$E_y = -\frac{dV_{ch}}{dy} = -\frac{I_D}{Z\mu_n C_{ox}\sqrt{(V_G - V_T)^2 - \frac{2I_D y}{Z\mu_n C_{ox}}}}$$



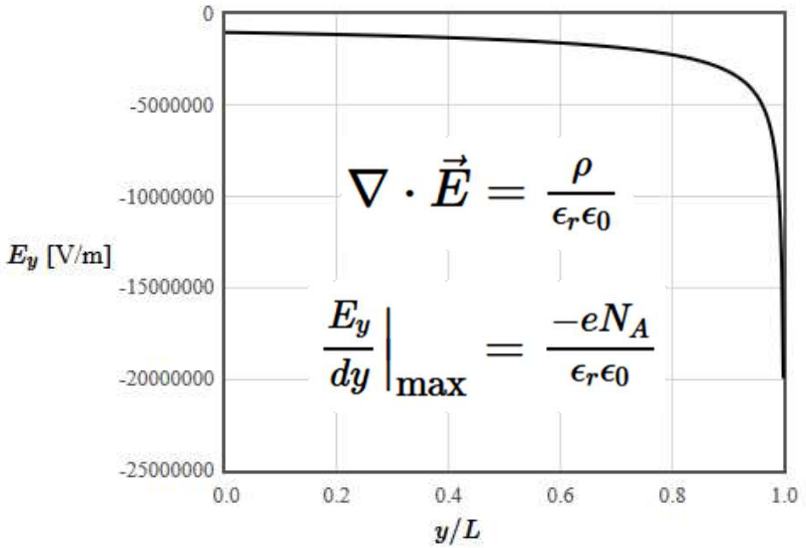


MOSFET Gradual Channel Approximation



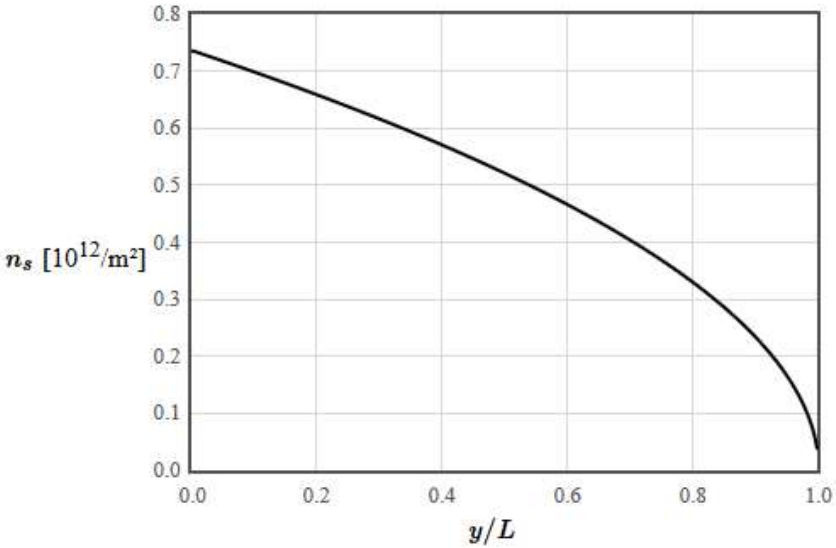
$Z =$	1E-5	m
$L =$	1E-6	m
$\mu_n =$	1500	cm²/Vs
$\epsilon_r =$	4	
$t_{ox} =$	3E-9	m
$V_D =$	1.9	V
$V_G =$	3	V
$V_T =$	1	V

Replot



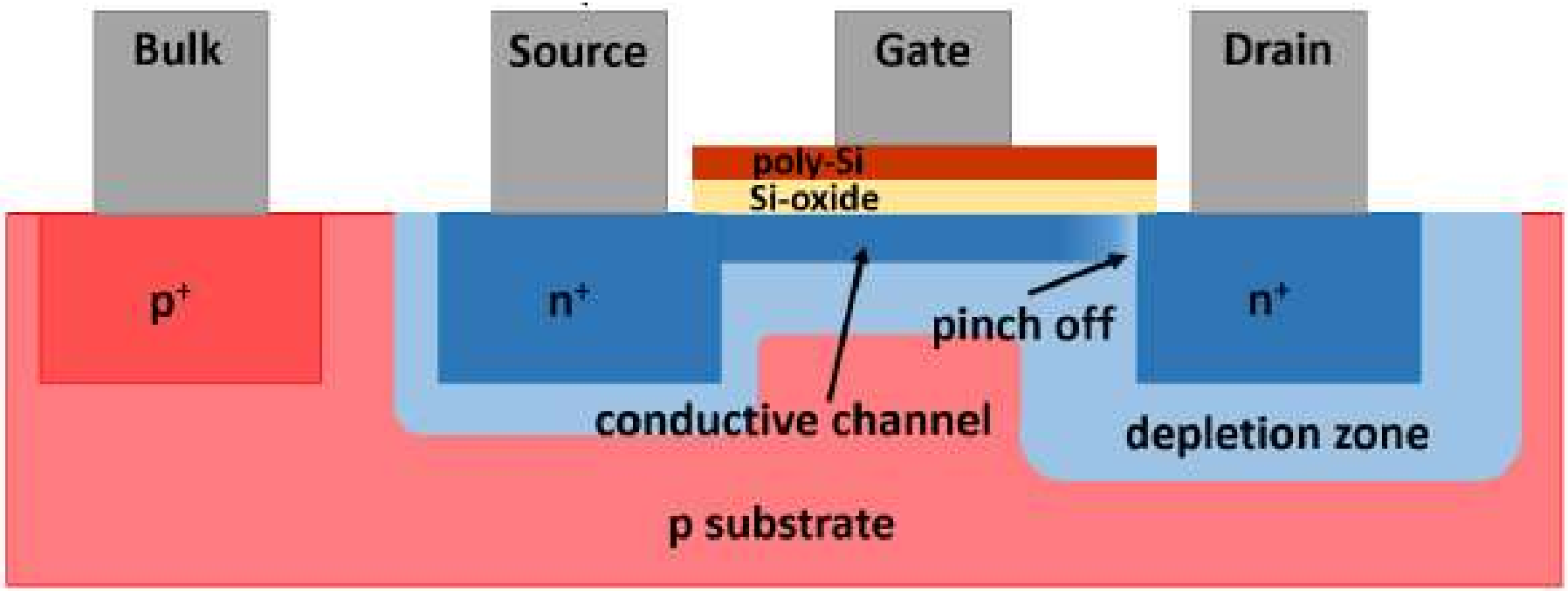
$$\nabla \cdot \vec{E} = \frac{\rho}{\epsilon_r \epsilon_0}$$

$$\left.\frac{E_y}{dy}\right|_{\max} = \frac{-eN_A}{\epsilon_r \epsilon_0}$$



http://lampx.tugraz.at/~hadley/psd/L10/gradualchannelapprox.php

MOSFET (saturation regime)

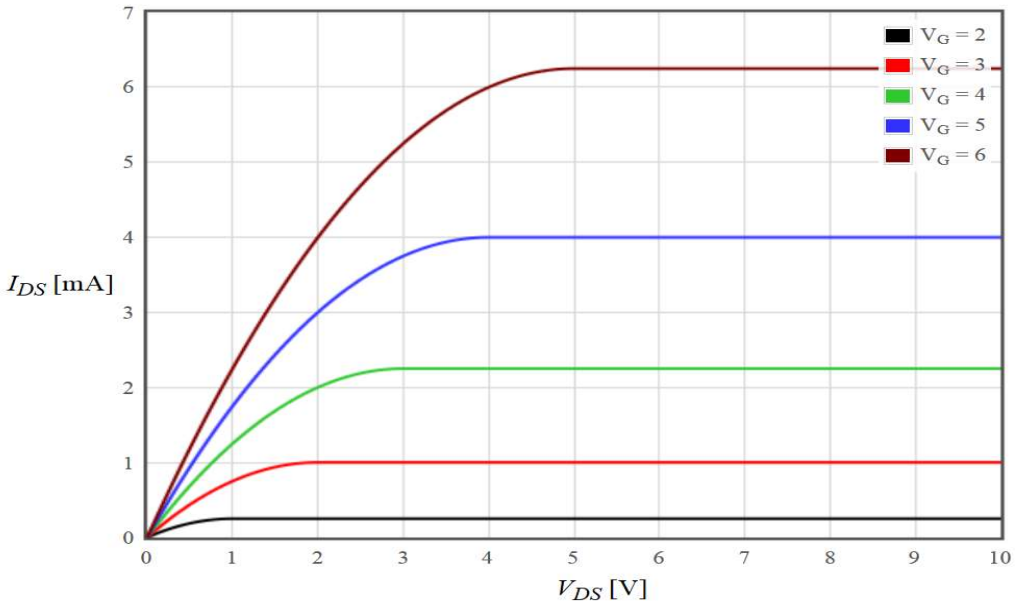


Gradual channel approximation

$$\int_0^L I_D \, \mathrm{d}y = \int_0^{V_D} Z \mu_n C_{ox} (V_G - V_{ch}(y) - V_T) \, \mathrm{d}V$$

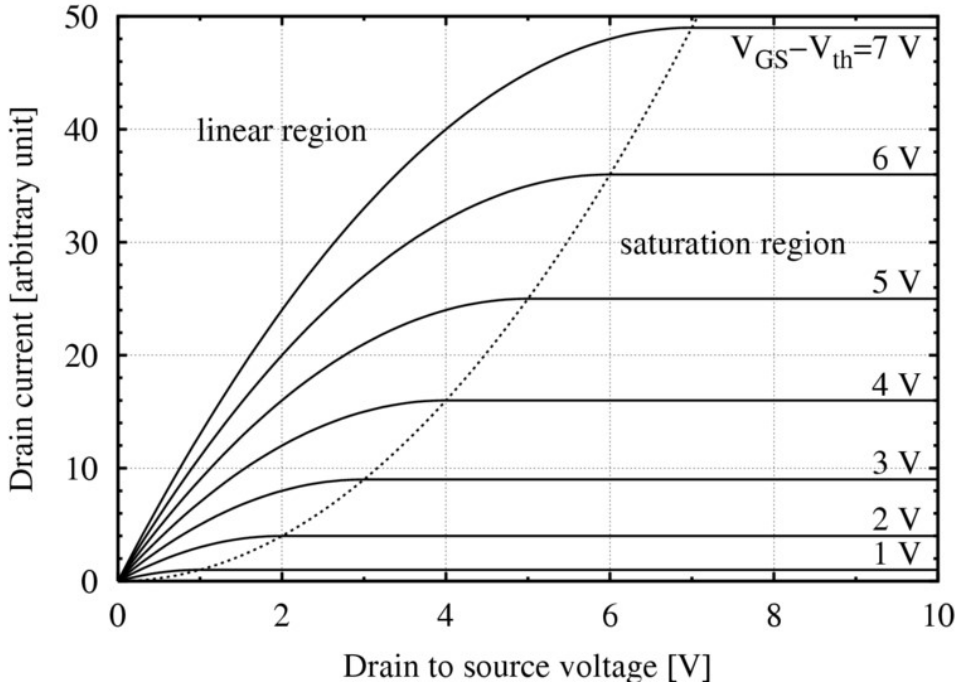
$$\boxed{I_D = \frac{Z}{L} \mu_n C_{ox} \left[(V_G - V_T) V_D - \frac{V_D^2}{2} \right]}$$

Valid in the linear regime (until pinch-off occurs at the drain).



MOSFET-saturation voltage

$$I = \frac{Z}{L}\mu_n C_{ox}\left[\left(V_G - V_T\right)V_D - \frac{V_D^2}{2}\right]$$



At pinch-off, $dI_{ds}/dV_{ds} = 0$

$$\frac{dI}{dV_D} = \frac{Z}{L}\mu_n C_{ox}\left[\left(V_G - V_T\right) - V_D\right] = 0 \qquad V_{sat} = \left(V_G - V_T\right)$$

A MOSFET in saturation is a voltage controlled current source.

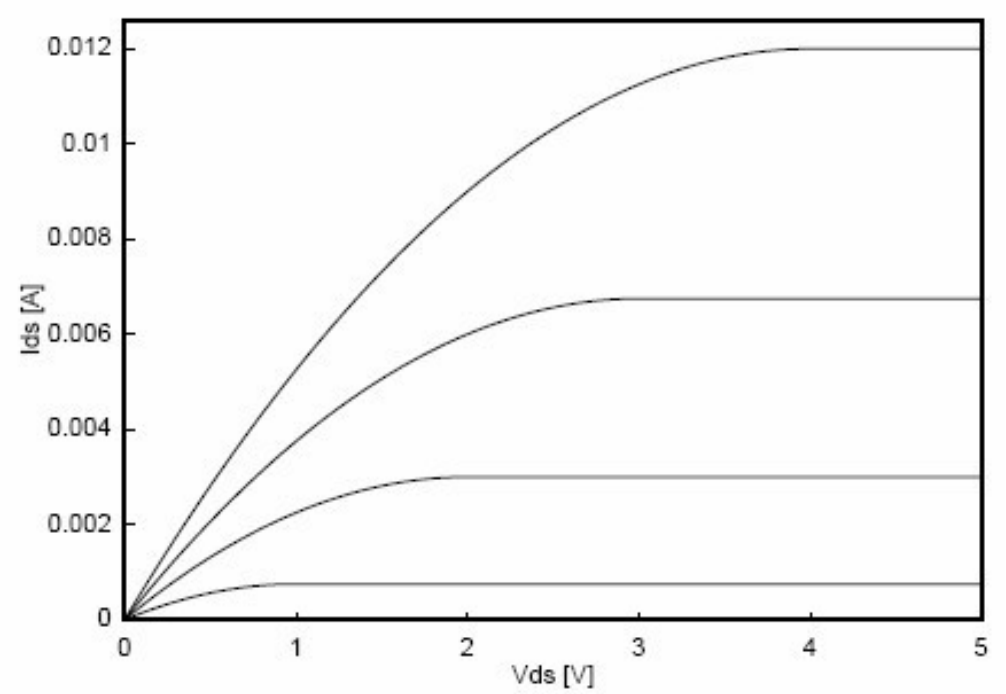
MOSFET - saturation current

Use the saturation voltage at pinch-off to determine the saturation current

$$V_{sat} = \left(V_G - V_T\right)$$

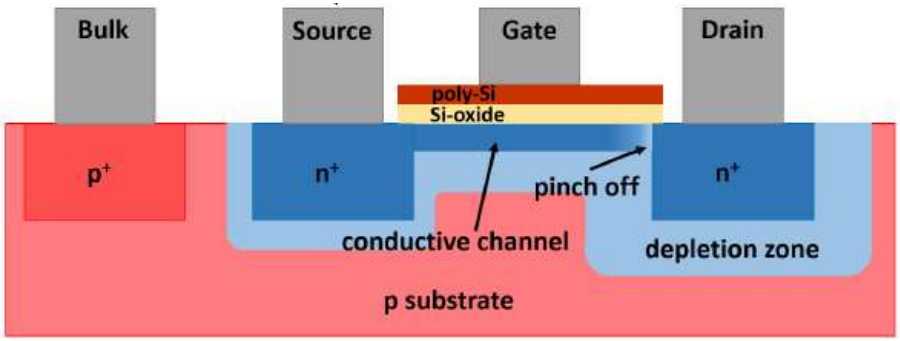
$$I = \frac{Z}{L}\mu_n C_{ox}\left[\left(V_G - V_T\right)V_D - \frac{V_D^2}{2}\right]$$

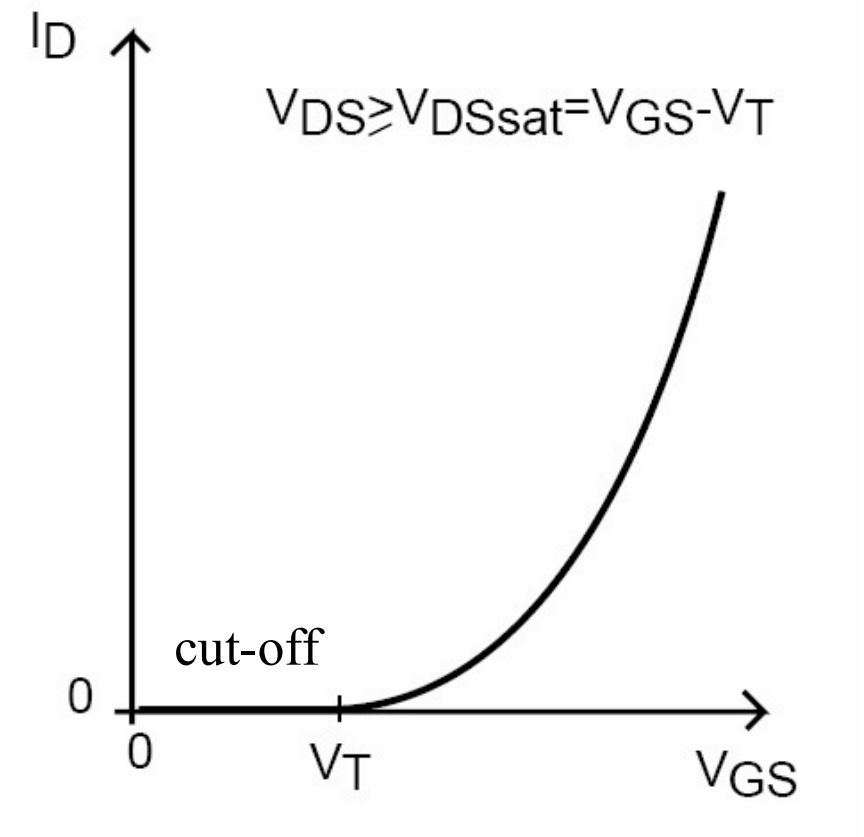
$$I_{sat} = \frac{Z}{2L}\mu_n C_{ox}\left(V_G - V_T\right)^2$$

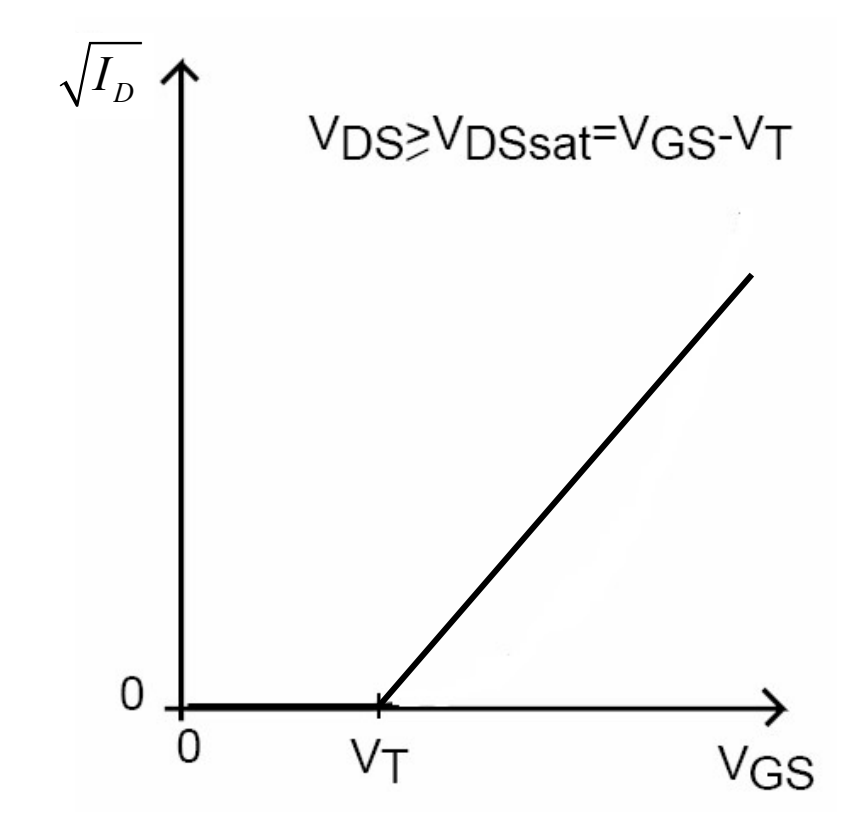


MOSFET (saturation regime)

$$I_{sat} = \frac{Z}{2L}\mu_n C_{ox}\left(V_{GS} - V_T\right)^2$$





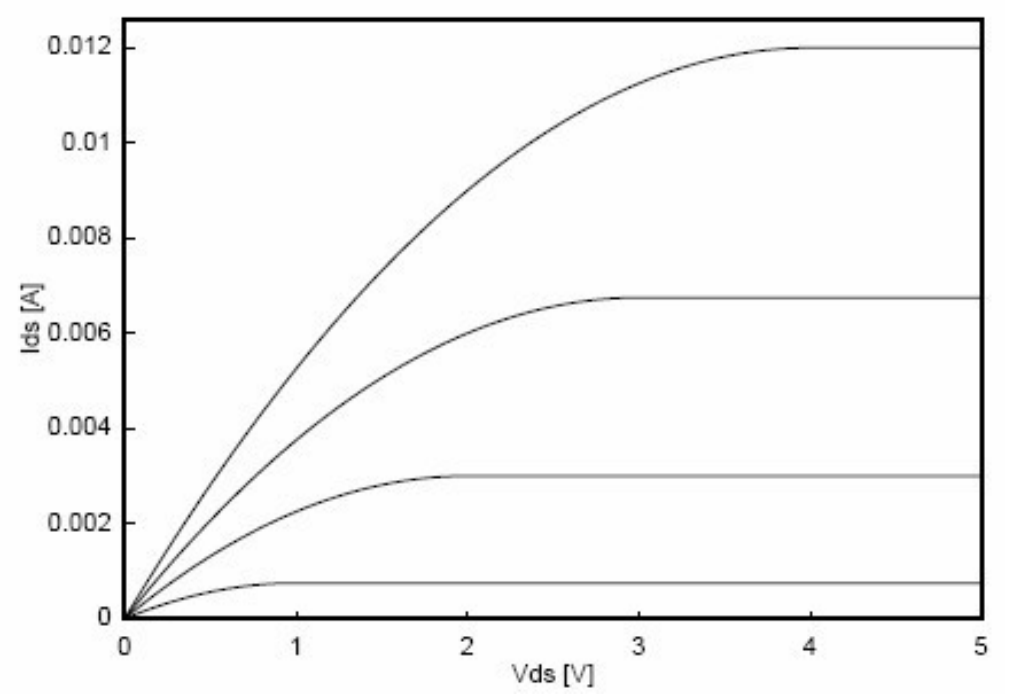


MOSFET (linear regime)

Channel conductance in the linear regime. For small V_D

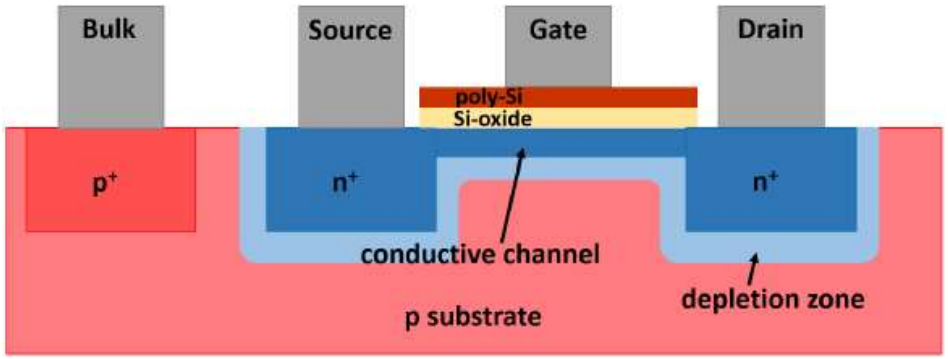
$$I \approx \frac{Z}{L}\mu_n C_{ox}\left[\left(V_G - V_T\right)V_D\right]$$

$$g_D = \frac{dI_D}{dV_D} = \frac{Z}{L}\mu_n C_{ox}\left(V_G - V_T\right)$$

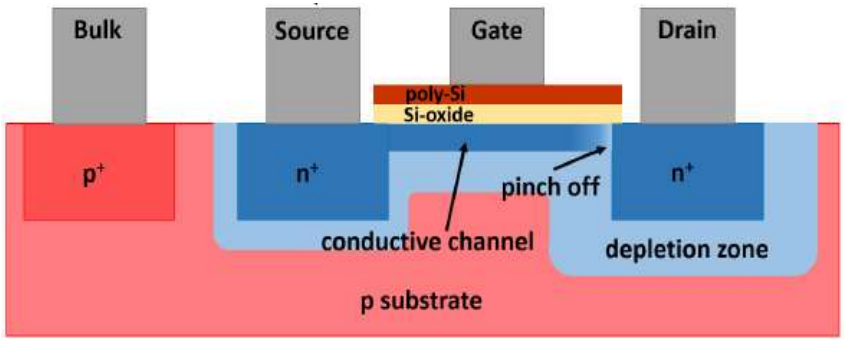


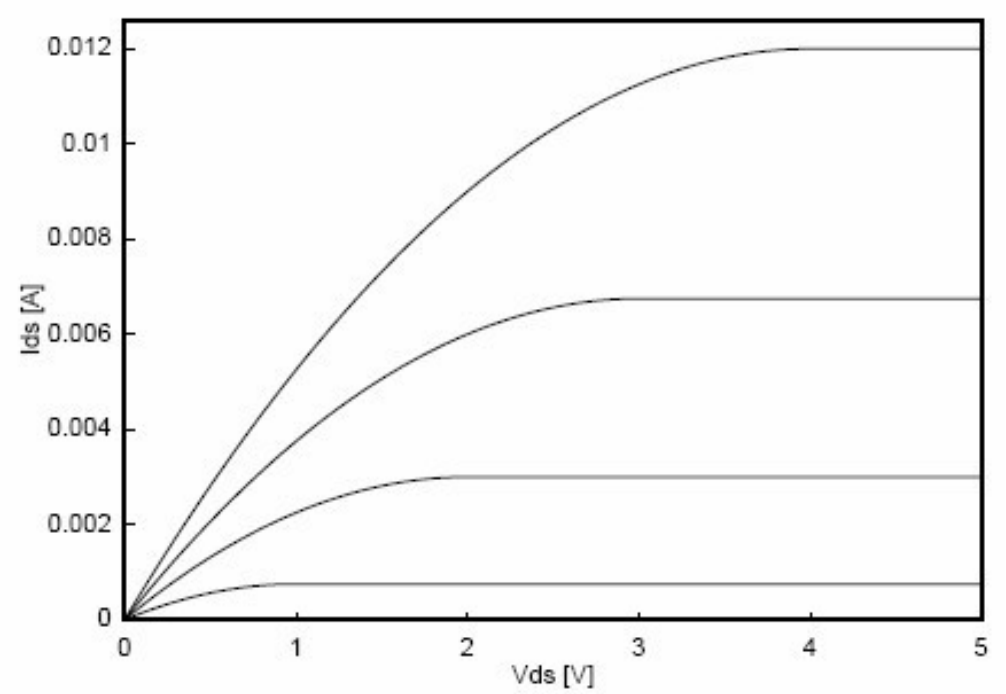
Transconductance

$$g_m = \frac{dI_D}{dV_G} = \frac{Z}{L}\mu_n C_{ox} V_D$$



MOSFET (saturation regime)





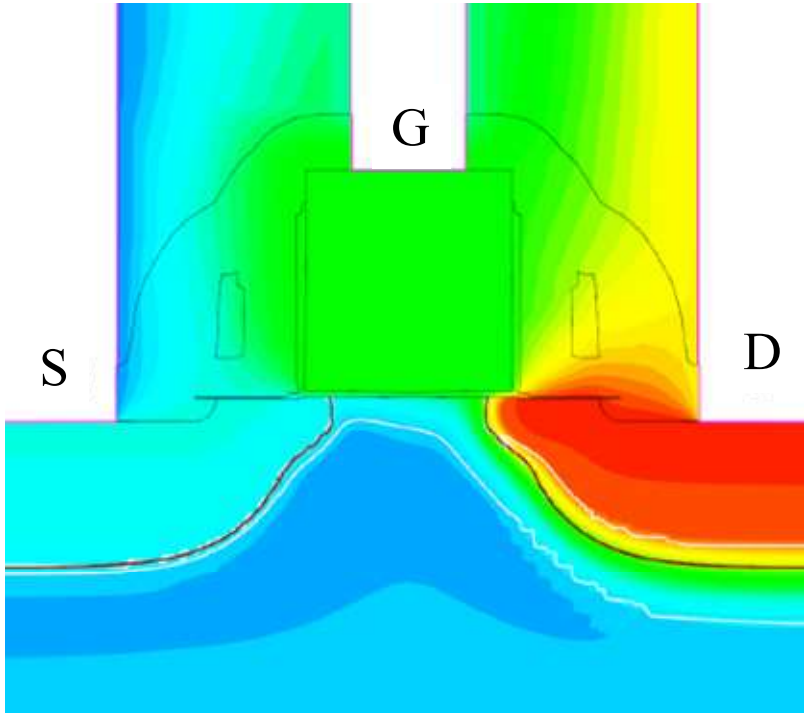
$$I_{sat} = \frac{Z}{2L}\mu_n C_{ox}\left(V_G - V_T\right)^2$$

Transconductance

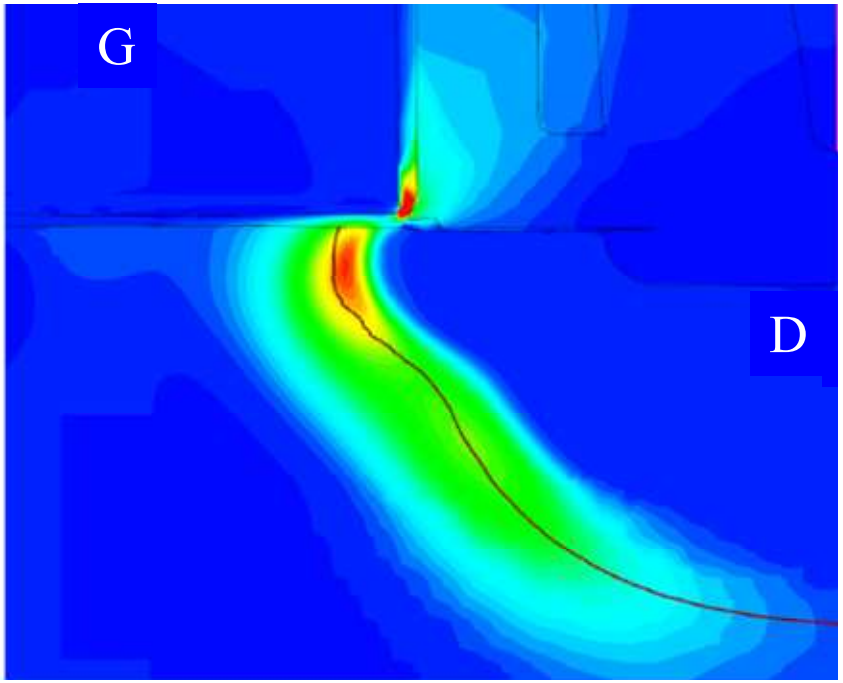
$$g_m = \frac{dI_D}{dV_G} = \frac{Z}{L}\mu_n C_{ox}\left(V_G - V_T\right)$$

A MOSFET in the saturation regime acts like a voltage controlled current source.

Saturation



Potential

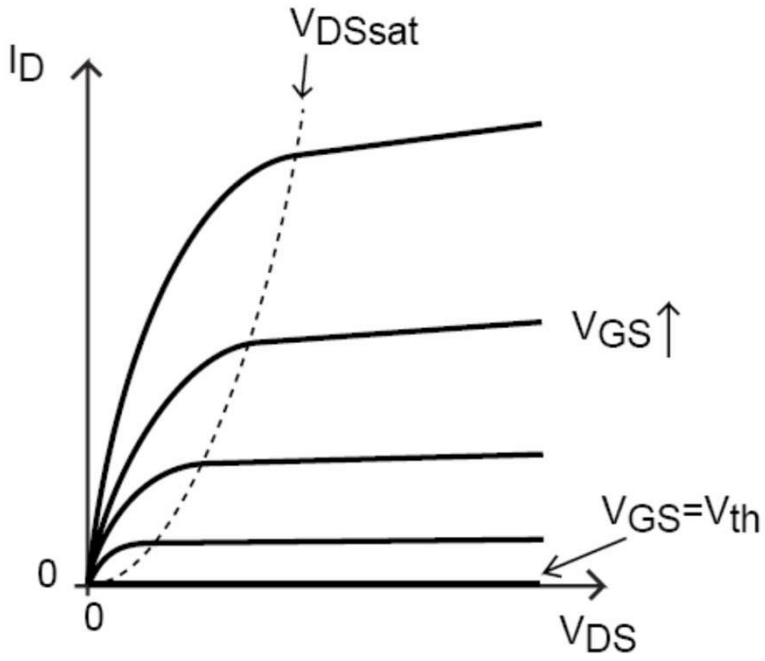


Electric field strength

Alexander Schiffmann, Master Thesis (2016)

MOSFET (saturation regime)

$$I_{sat} = \frac{Z}{2L}\mu_n C_{ox}\left(V_G - V_T\right)^2\left(1-\lambda\left(V_D - V_{sat}\right)\right)$$



Experimentally: channel length modulation

$$\lambda \propto \frac{1}{L}$$

High frequencies

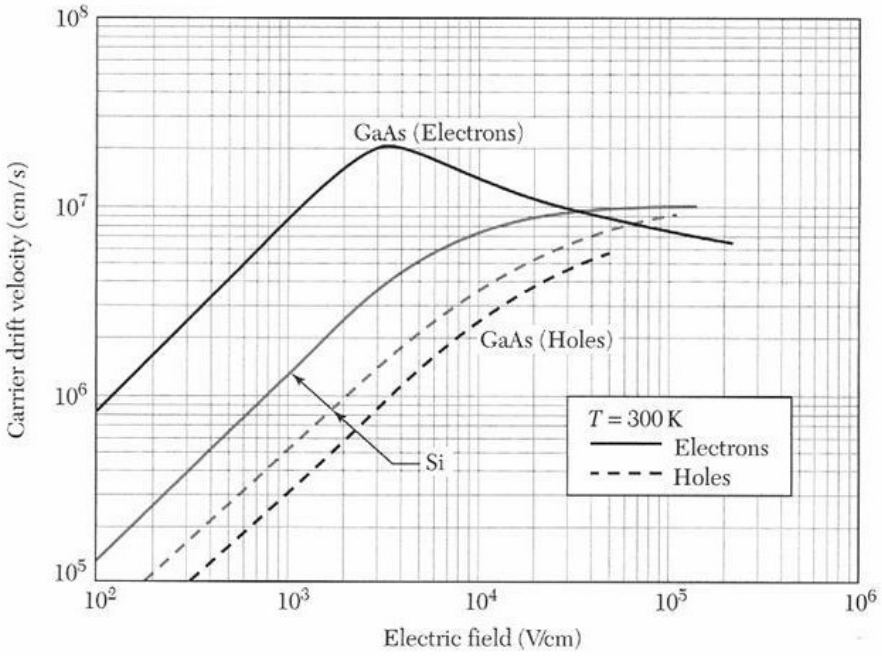
$$\tilde{i}_{in} = 2\pi f C_G \tilde{v}_G \qquad \tilde{i}_{out} = g_m \tilde{v}_G$$

$$\tilde{i}_{in} < \tilde{i}_{out}$$

$$f < \frac{g_m}{2\pi C_G} \propto \frac{1}{L^2} = f_T$$

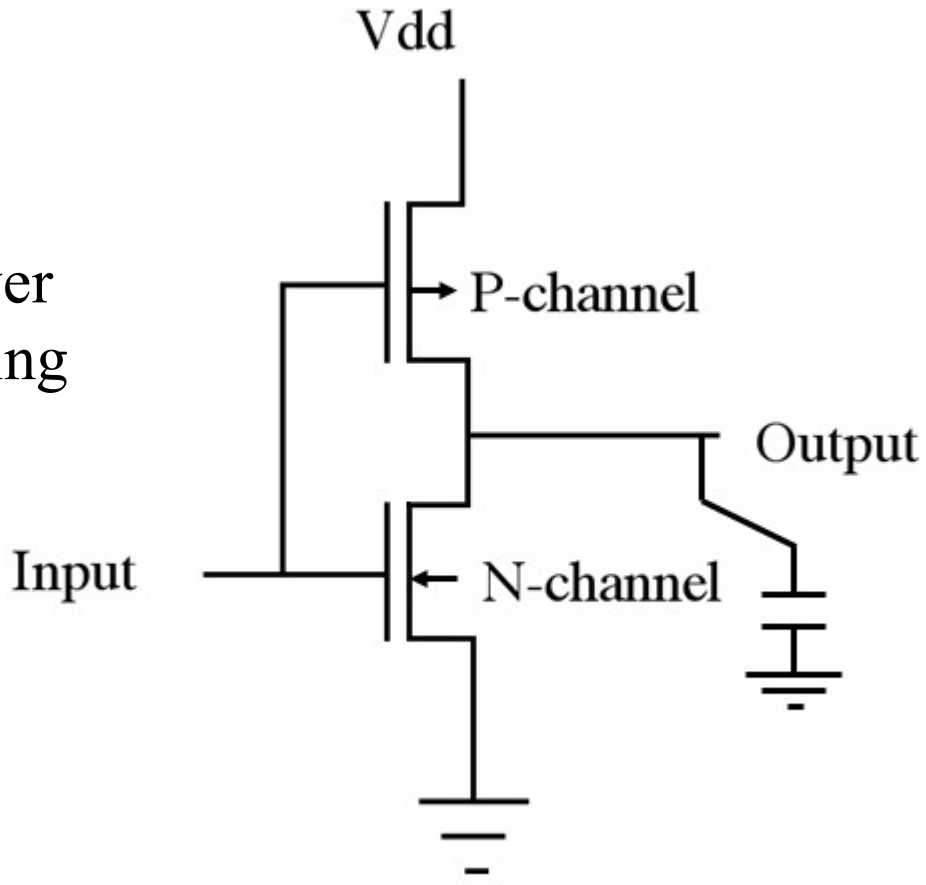
For large E, Ohm's law ($j = ne\mu E$) is not valid. The electron velocity saturates. For velocity saturation:

$$f_T \approx \frac{v_s}{L}$$



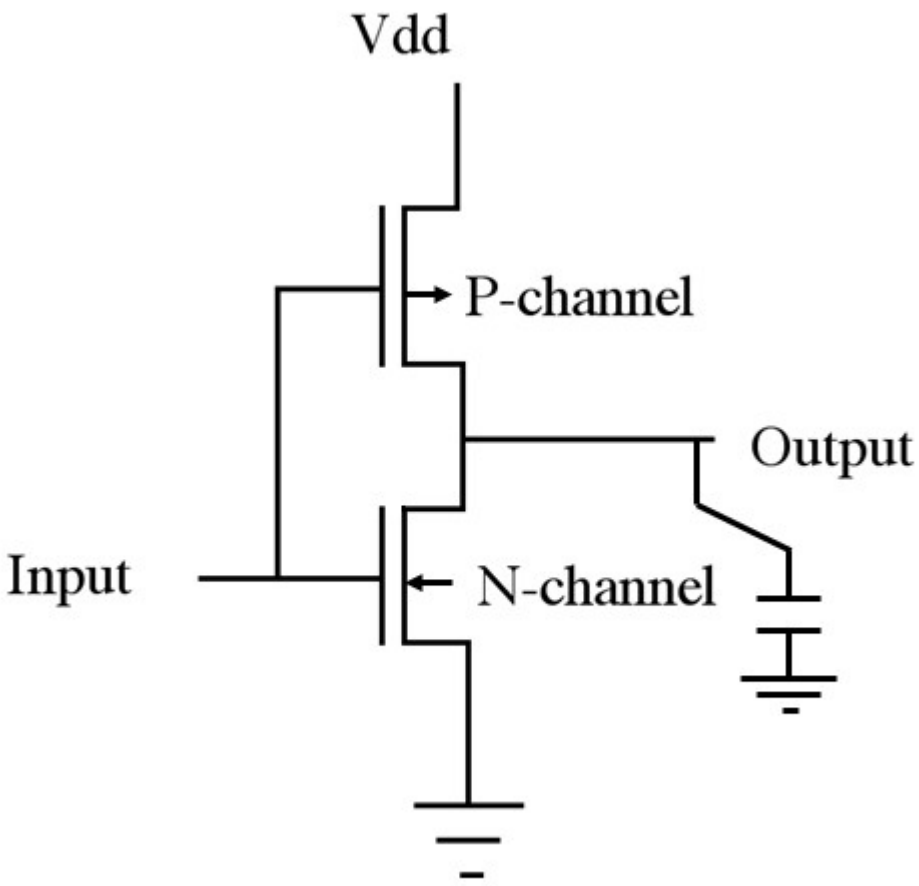
CMOS inverter

Dissipates little power
except when switching

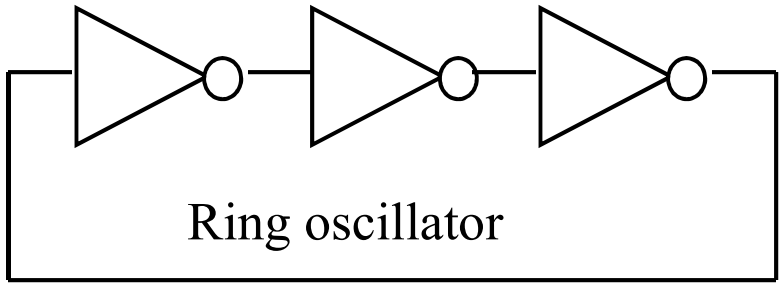


$$E = QV_{dd} = CV_{dd}^2$$

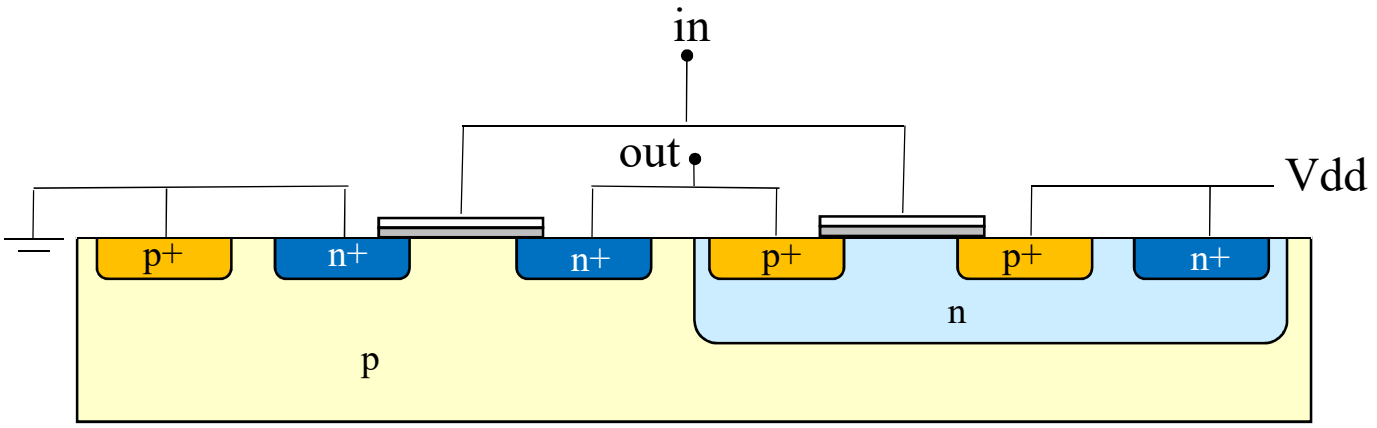
Gate delay

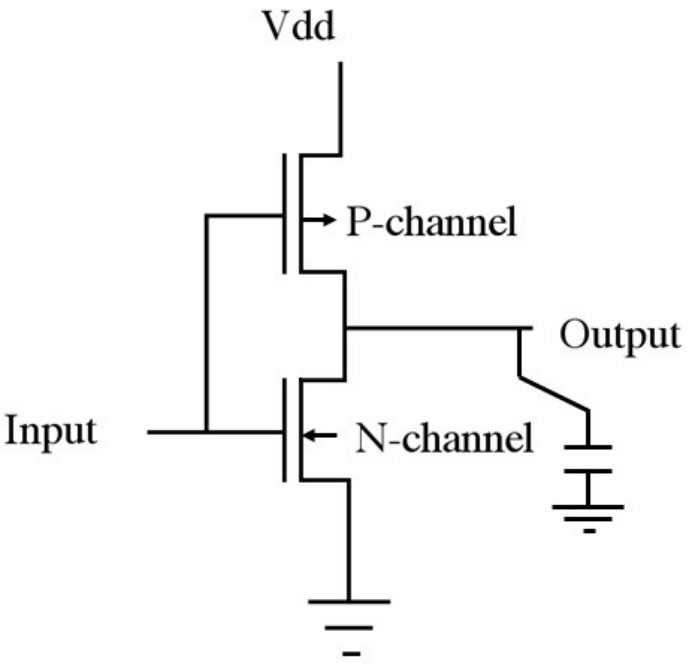


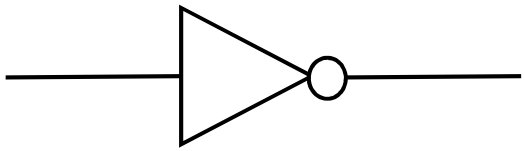
Gate delay is limited by $C_{gate}V_{dd}/I$.



CMOS inverter

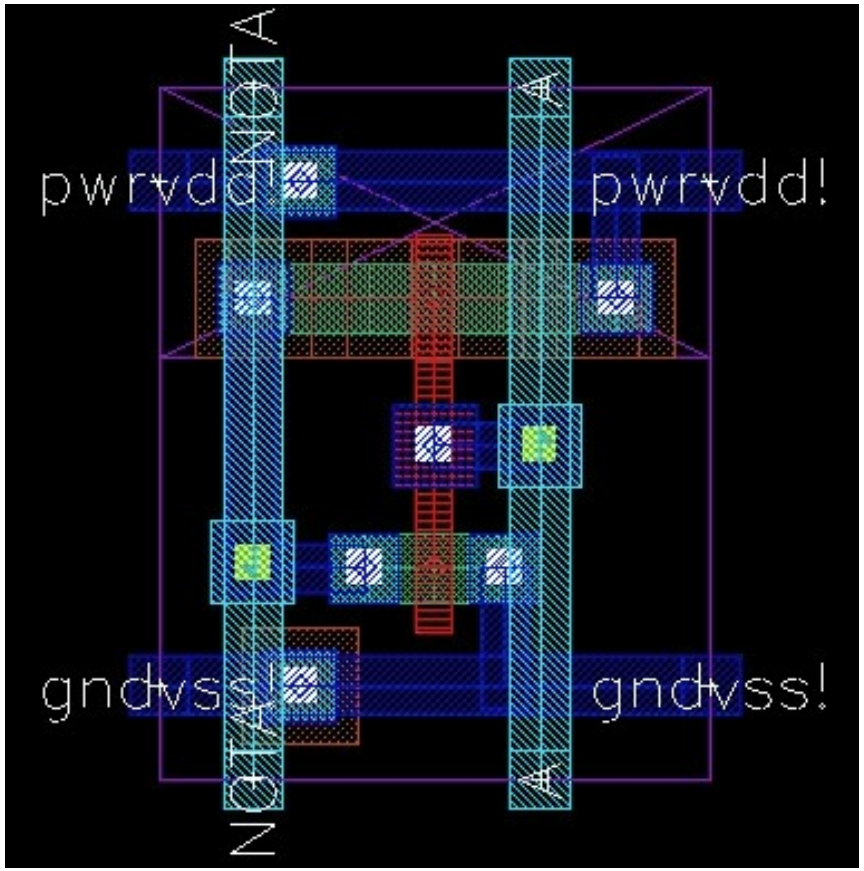


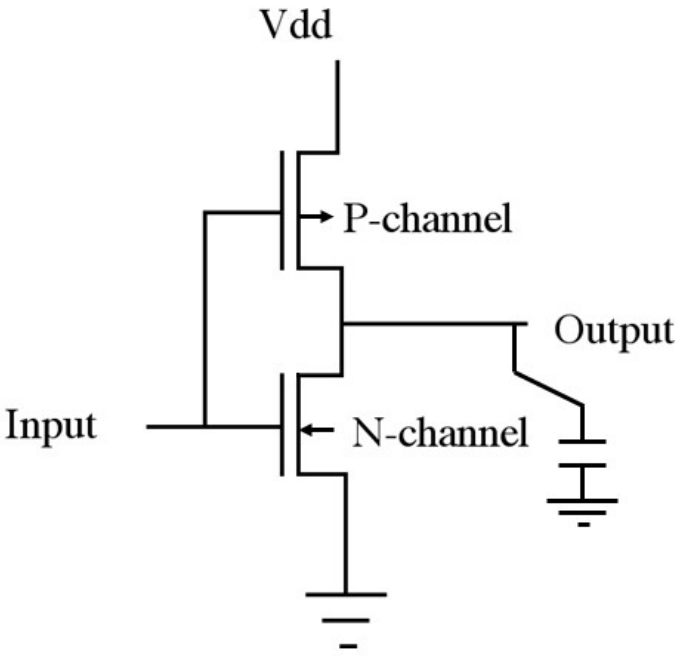


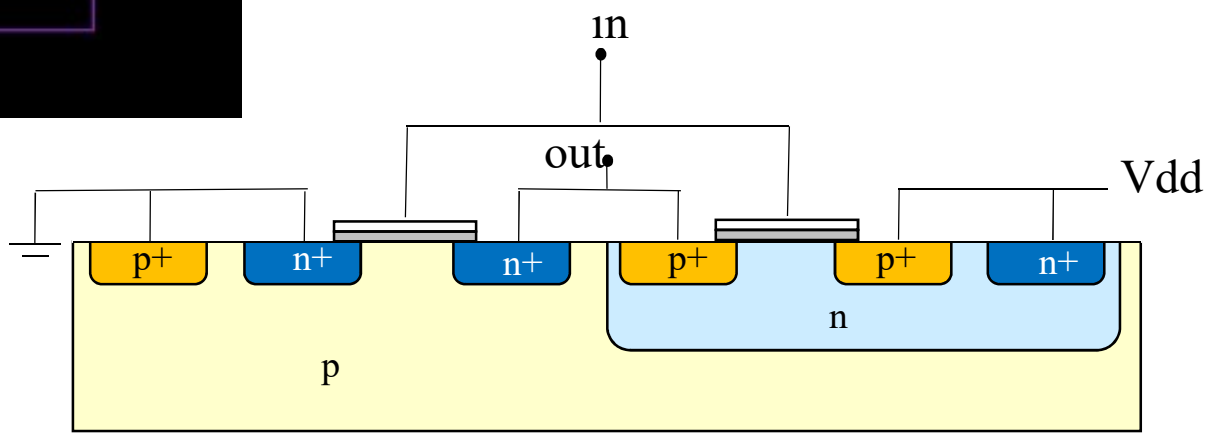


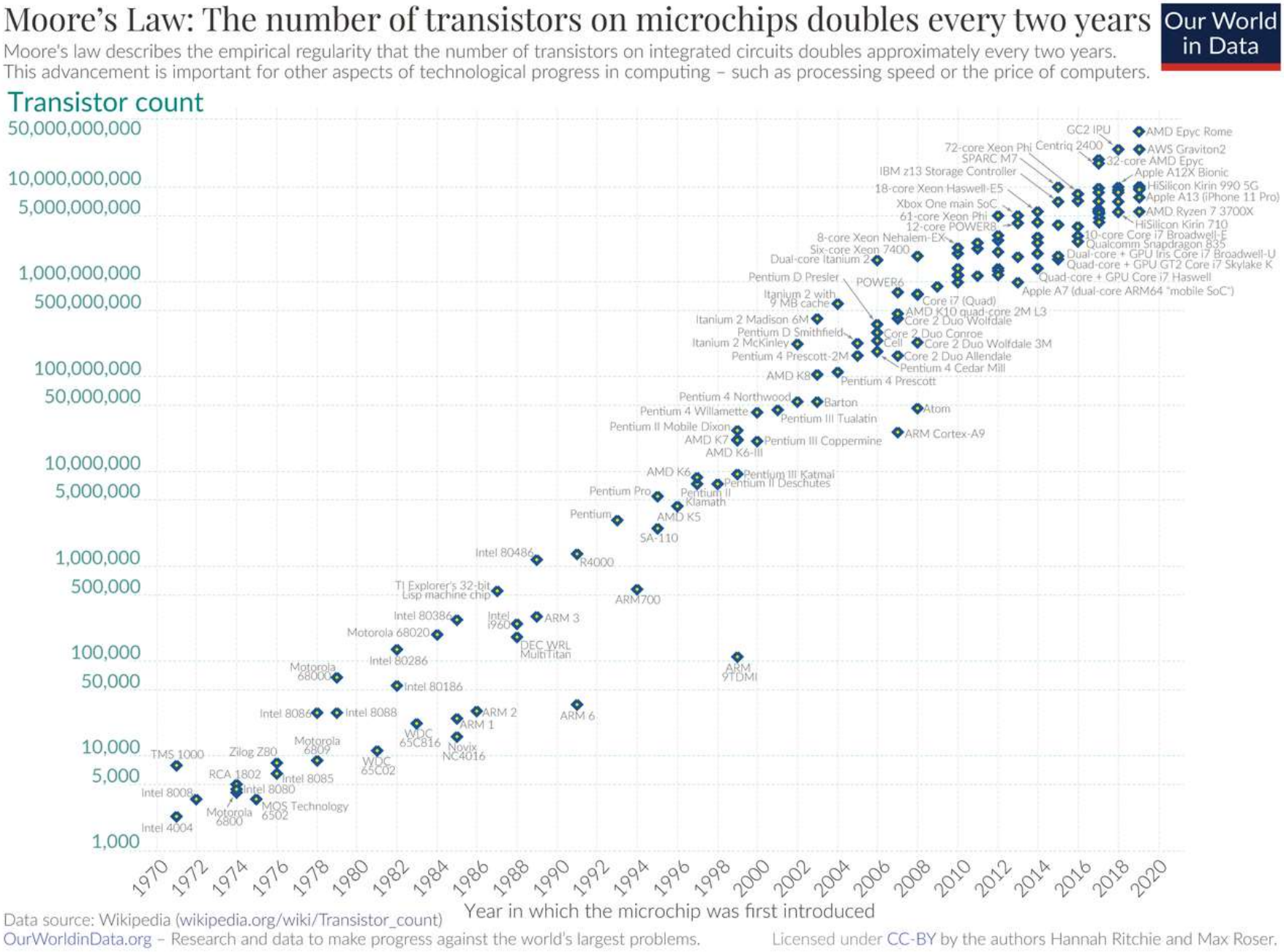
inverter

CMOS inverter



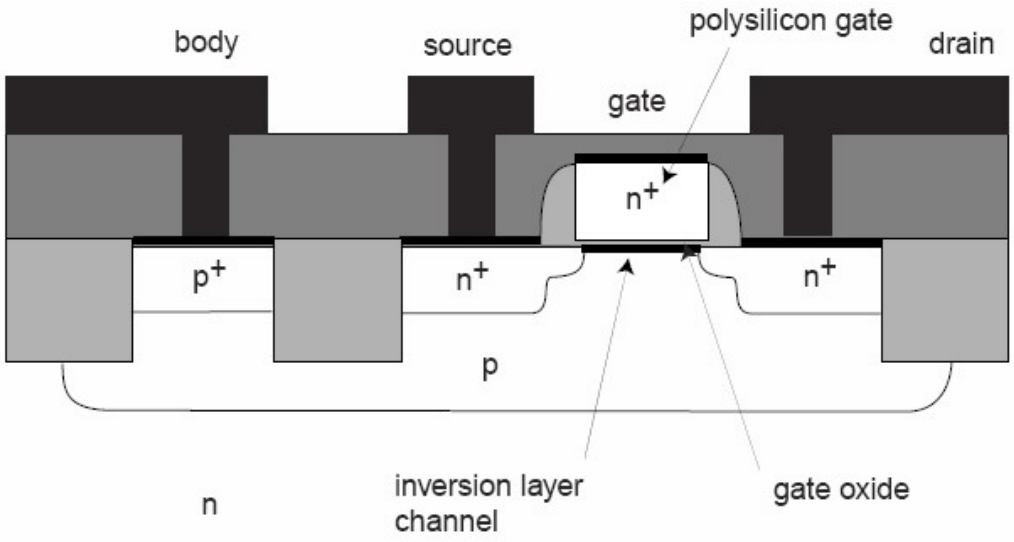






By Max Roser, Hannah Ritchie - https://ourworldindata.org/uploads/2020/11/Transistor-Count-over-time.png, CC BY 4.0, https://commons.wikimedia.org/w/index.php?curid=98219918

Constant E-field Scaling



Gate length L, transistor width Z, oxide thickness t_{ox} are scaled down.

V_{ds}, V_{gs}, and V_T are reduced to keep the electric field constant.

Power density remains constant.

$$L \sim 45\ t_{ox}$$

1975 - 1990: "Days of happy scaling"

Constant E-field scaling

$$I_{sat} = \frac{Z}{2L}\mu_n \frac{\varepsilon_{ox}}{t_{ox}}\left(V_G - V_T\right)^2$$

$$L \Rightarrow sL, \qquad Z \Rightarrow sZ, \qquad t_{ox} \Rightarrow st_{ox}, \qquad V_{th} \Rightarrow sV_{th}$$

$$I_{sat} \Rightarrow sI_{sat} \quad \longleftarrow \quad I_{sat} \text{ gets smaller}$$

$$g_m = \frac{dI_D}{dV_G} = \frac{Z}{L}\mu_n \frac{\varepsilon_{ox}}{t_{ox}}\left(V_G - V_T\right) \quad \longleftarrow \quad \text{Transconductance stays the same.}$$

Power per transistor decreases like L^2. Power per unit area remains constant.

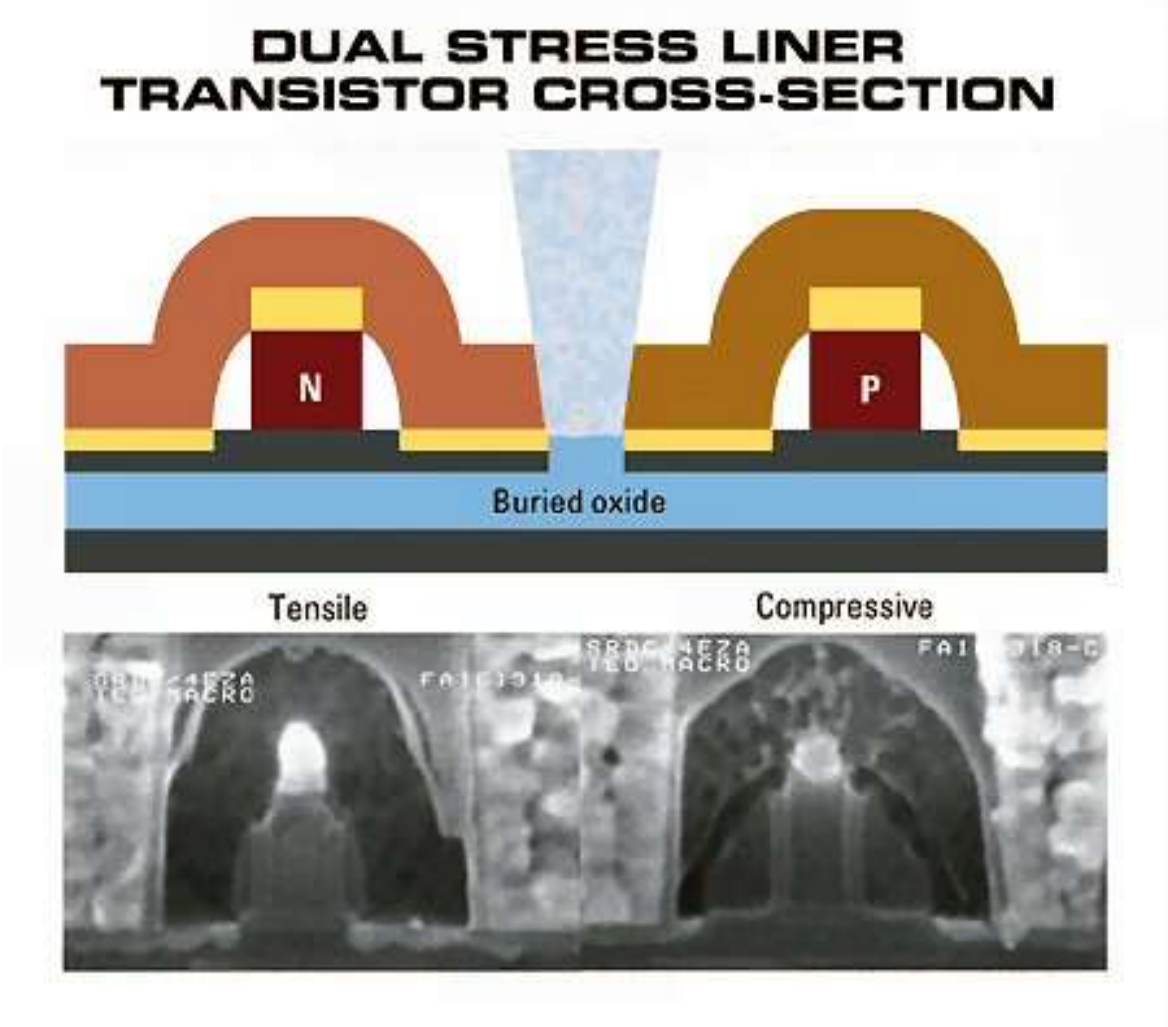
The heat dissipation problem

Microprocessors are hot ~ 100 C
Hotter operation will cause dopants to diffuse

When more transistors are put on a chip they must dissipate less power.

Power per transistor decreases like L^2.

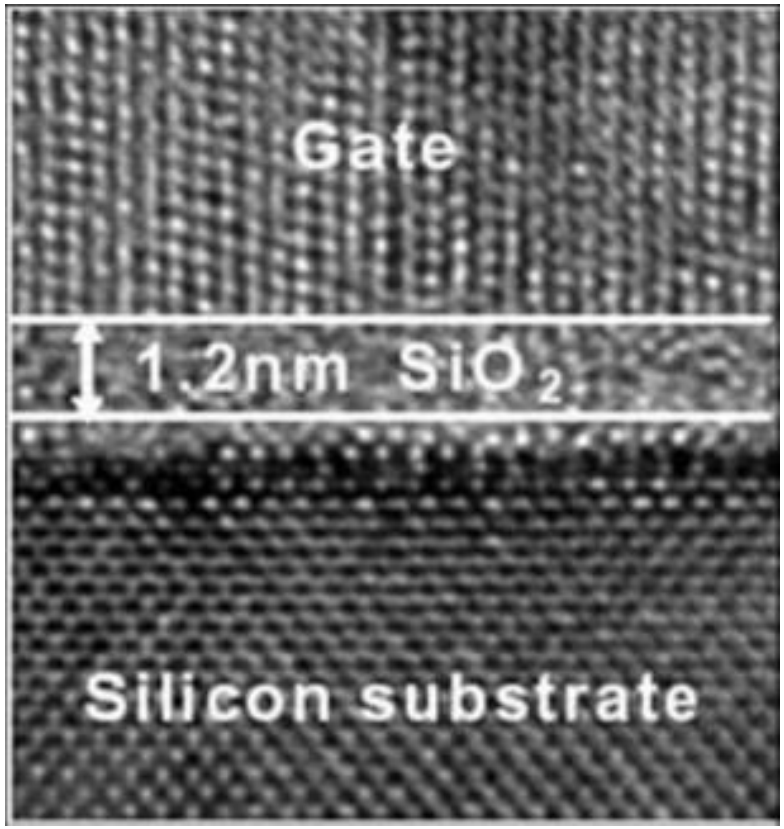
Dual stress liners



Tensile silicon nitride film over the NMOS and a compressive silicon nitride film over the PMOS improves the mobility.

http://www.xbitlabs.com/articles/cpu/display/athlon64-venice_2.html

Gate dielectric



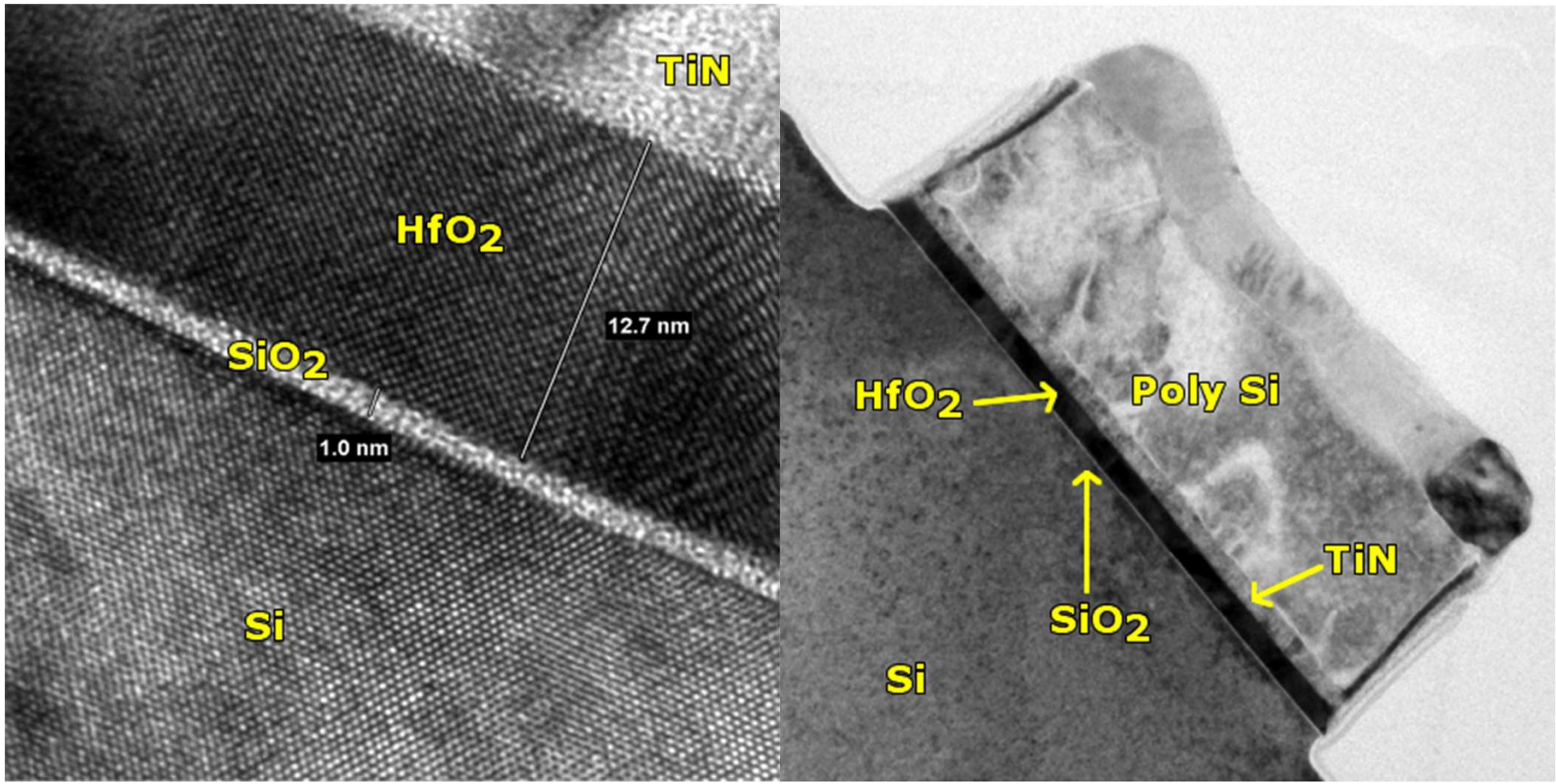
Thinner than 1 nm: electrons tunnel

Large dielectric constant desirable

$\varepsilon_r(SiO_2) \sim 4$

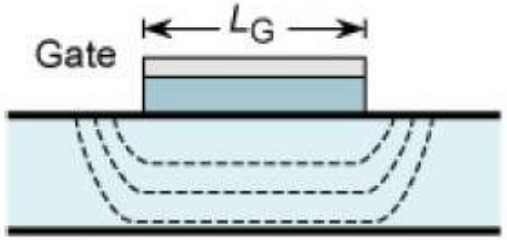
$\varepsilon_r(Si_3N_4) \sim 7$

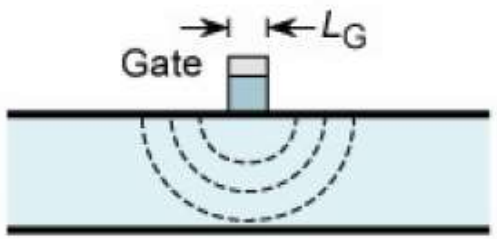
High-k dielectrics

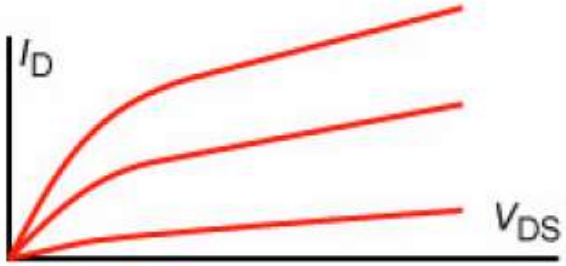


http://nano.boisestate.edu/research-areas/gate-oxide-studies/

Short channel effects







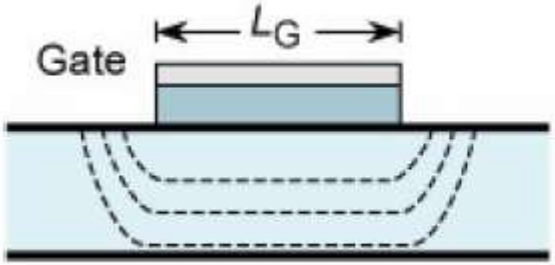
Short-channel effects:

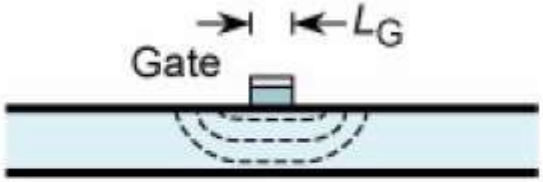
Threshold-voltage shift

Lack of pinch-off

Increased leakage current

Increase of output conductance





SOI: silicon on insulator

© E. F. Schubert, Rensselaer Polytechnic Institute, 2003

CMOS SOI

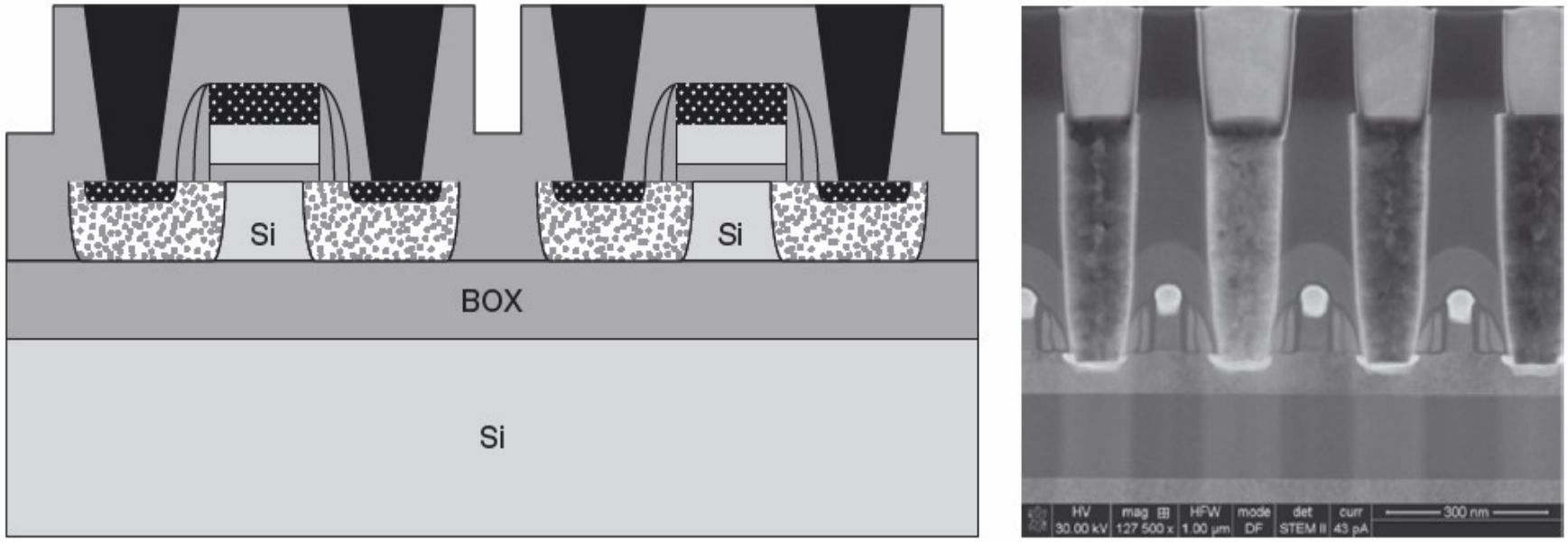
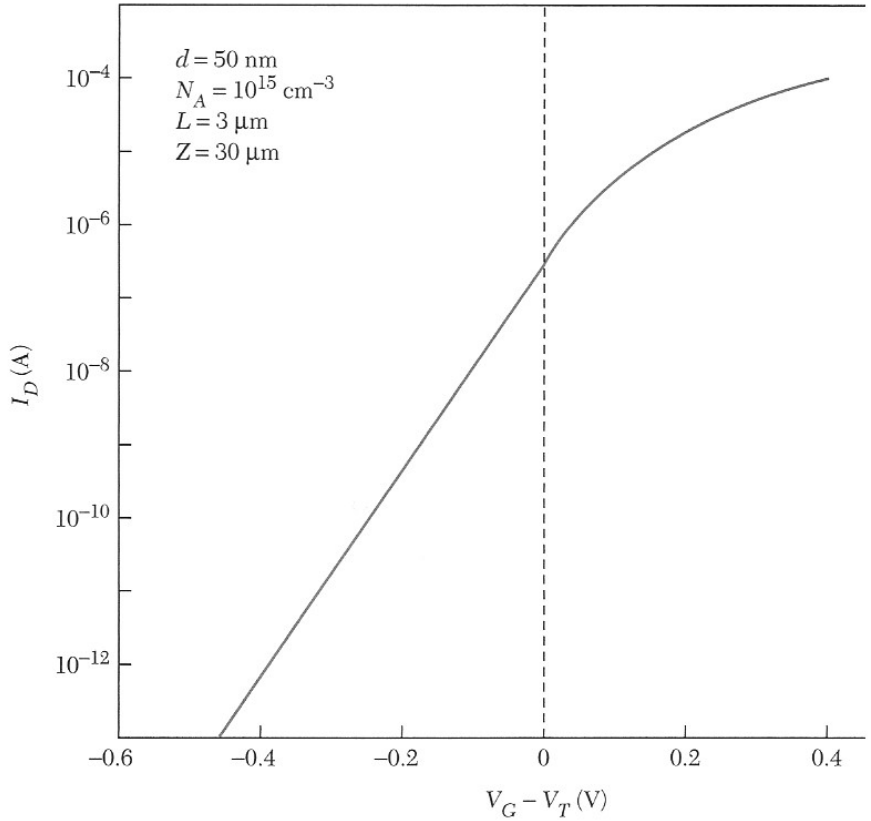


Figure 26.16 SOI MOSFET with first-level metal, schematic and TEM. Courtesy Brandon Van Leer, FEI Company4

Fransila

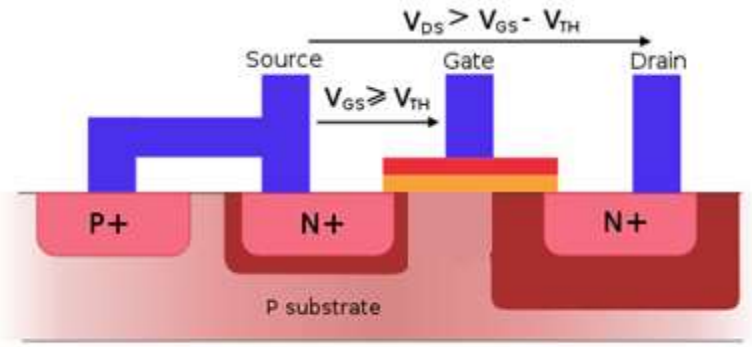
Subthreshold current

For $V_G < V_T$ the transistor should switch off but there is a diffusion current. The current is not really off until ~ 0.5 V below the threshold voltage.



Weak inversion

$$I_D \propto \exp\left(\frac{e(V_G - V_T)}{k_B T}\right)$$

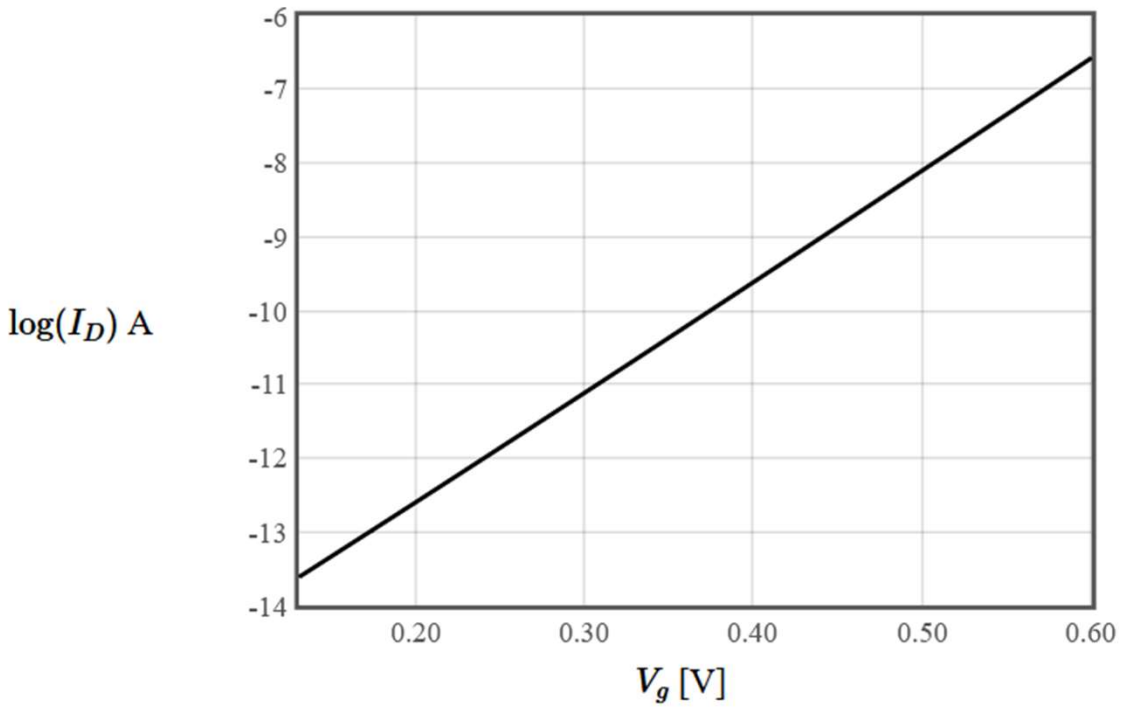


Subthreshold swing: 70-100 mV/decade

Subthreshold current

$$x_p = -\frac{\epsilon_s}{\epsilon_{\text{ox}}} t_{\text{ox}} + \sqrt{\left(\frac{\epsilon_s}{\epsilon_{\text{ox}}} t_{\text{ox}}\right)^2 + \frac{2\epsilon_s}{eN_A}(V_g - V_{fb})}$$

$$I_D \approx \frac{k_B T \mu W n_{2d}}{L} = \frac{n_i^2 \mu \epsilon_s k_B^2 T^2 W}{e^2 N_A^2 x_p L} \exp\left(\frac{e^2 N_A x_p^2}{2\epsilon_s k_B T}\right)$$



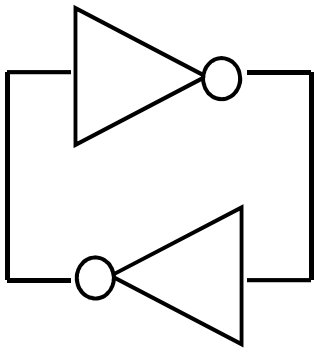
Subthreshold slope: 66 mV/decade

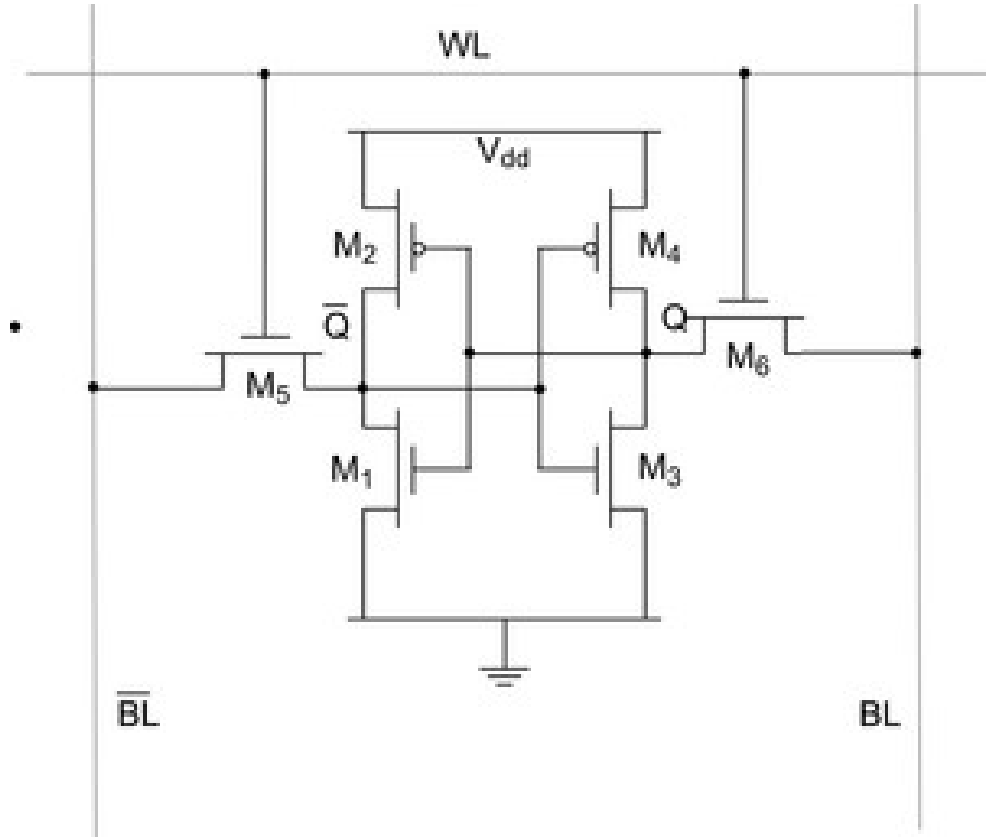
http://lampz.tugraz.at/~hadley/psd/L10/moscap_da.php

Memories

SRAM

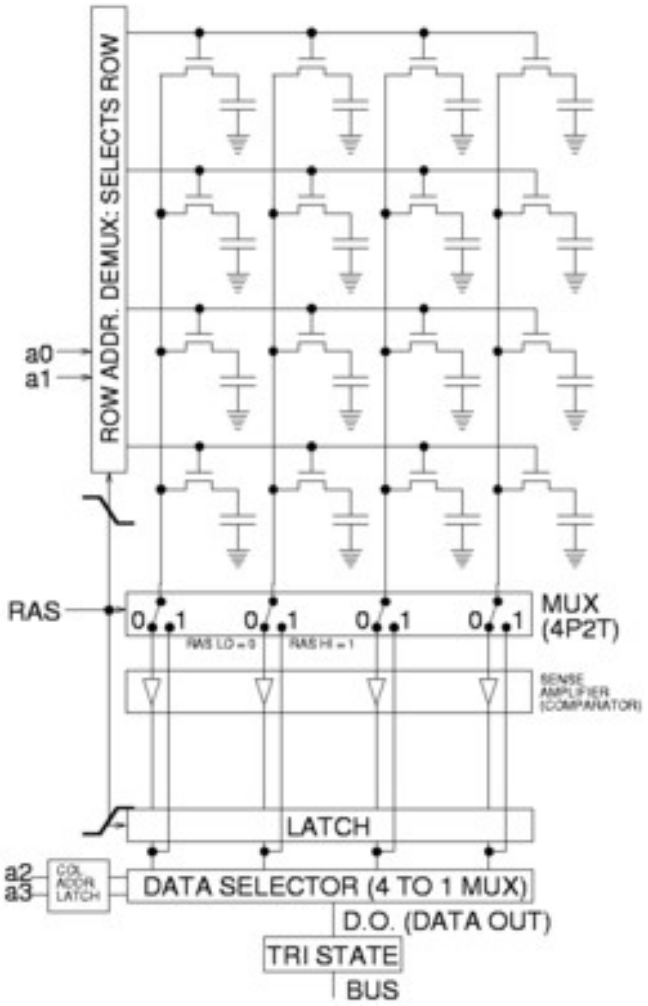
Static random access memory





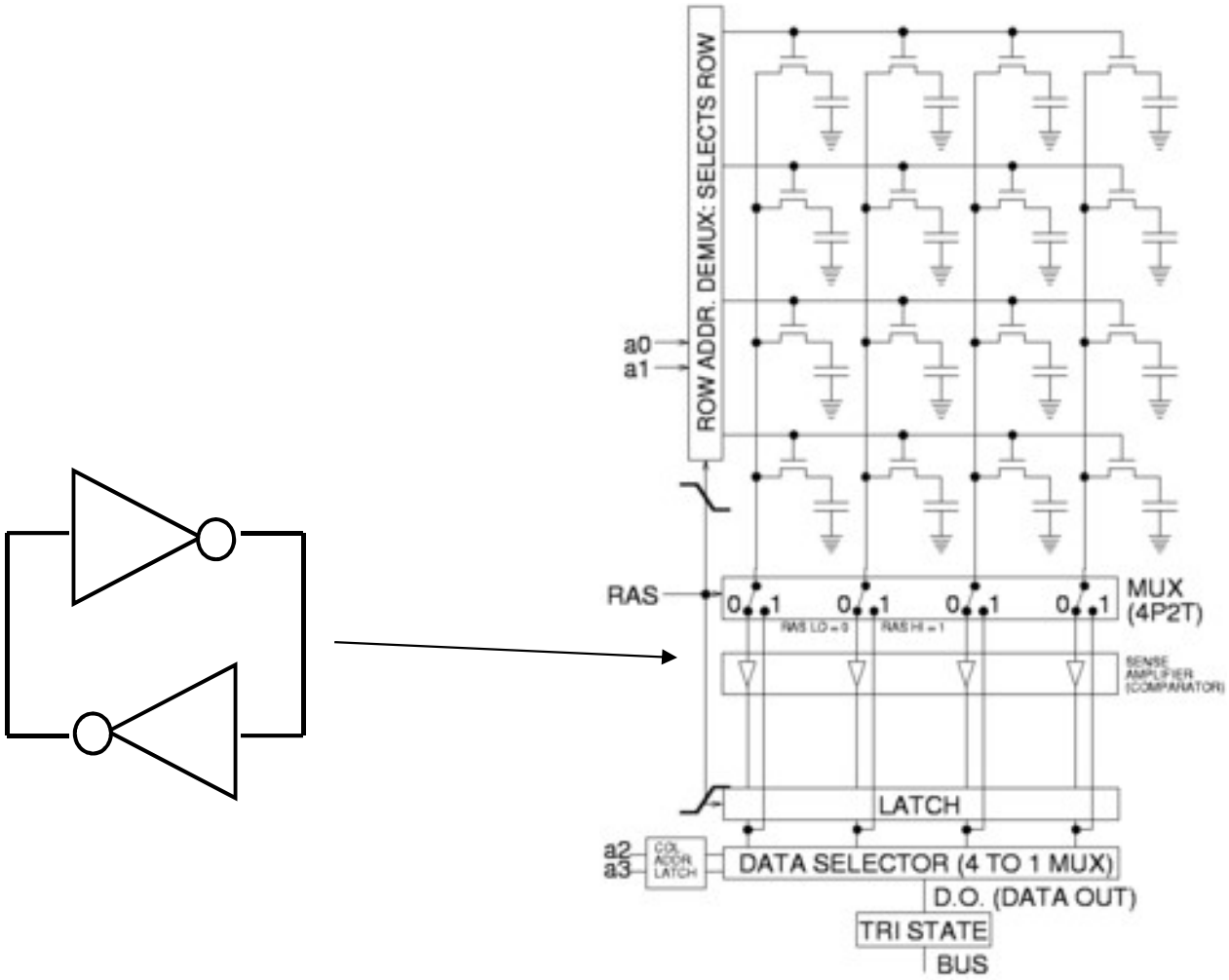
DRAM

Dynamic random access memory

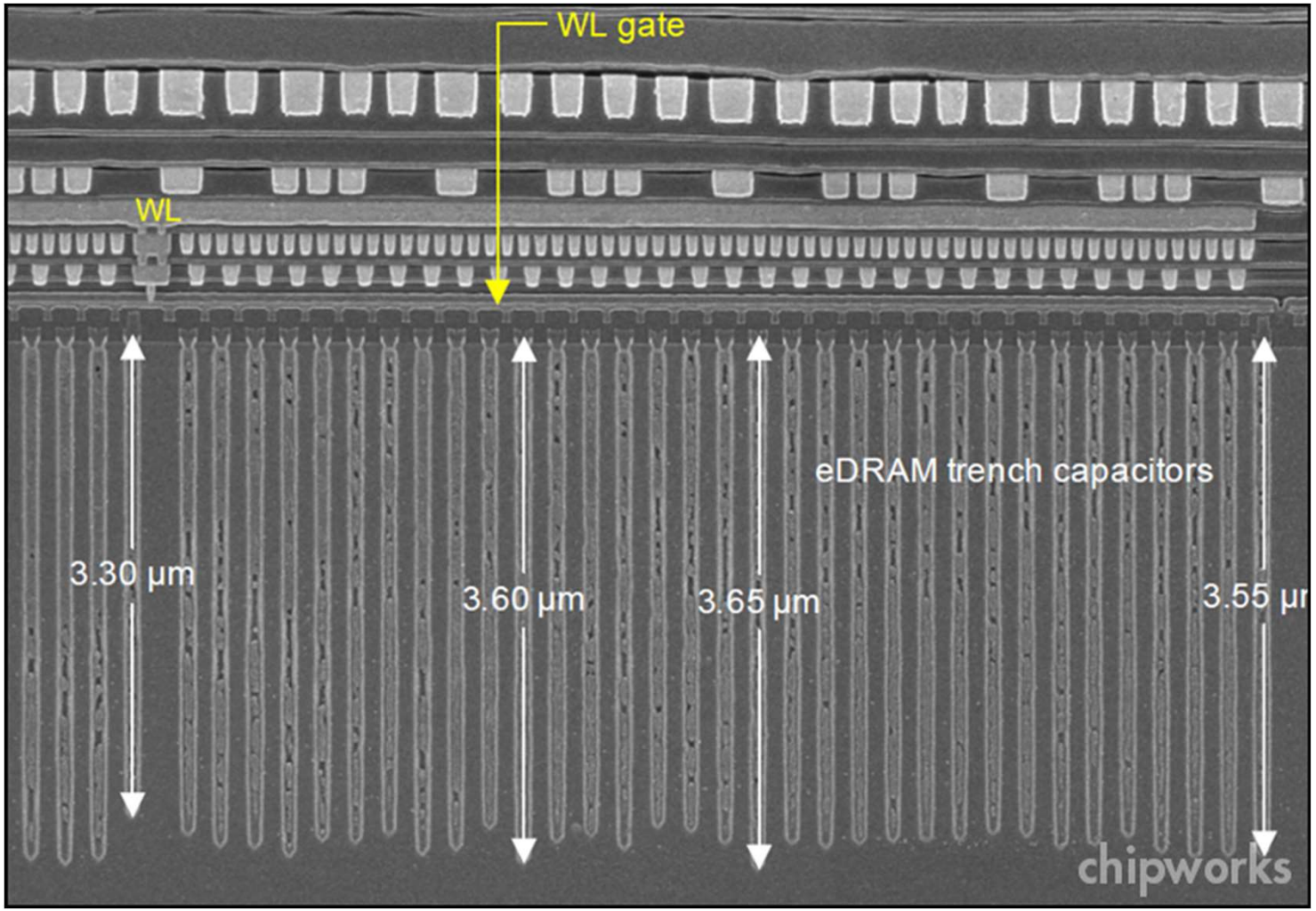


DRAM

Read and refresh DRAM with a SRAM cell



DRAM

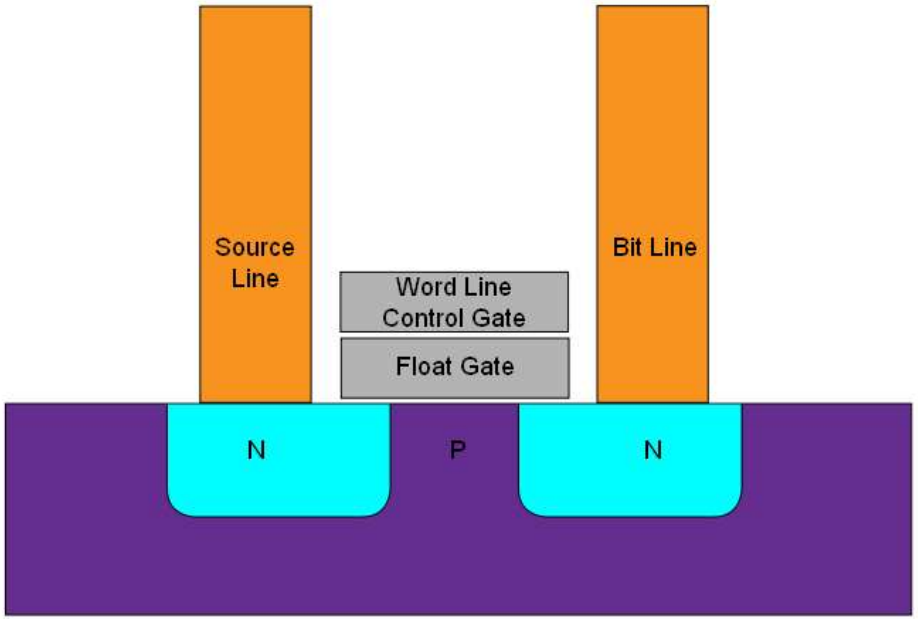


75:1

Silicon oxynitride SiO_xN_y dielectric

http://electroiq.com/chipworks_real_chips_blog/

Flash memory



Charge is stored on a floating gate

nonvolatile